

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Chou San Nelson Loke, et al.
Appl. No.	:	10/781,247
Filed	:	February 18, 2004
For	:	SYSTEM AND METHOD OF CVD CHAMBER CLEANING
Examiner	:	Keath Chen
Group Art Unit	:	1709

AMENDMENT AFTER FINAL**Mail Stop: AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed April 16, 2008, please reconsider the present application in light of the following amendments and comments.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.